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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2812

Examiner: Stanetta D. Isaac

In Re PATENT APPLICATION of:

Applicant(s): Jun KANAMORI

Serial No.: 10/634,851

Filing Date: August 6, 2003

For: SEMICONDUCTOR DEVICE
FABRICATION METHOD USING
OXYGEN ION IMPLANTATION

REQUEST FOR
RECONSIDERATION

OXYGEN ION IMPLANTATION

**MAE 292** 

August 11, 2005

Mail Stop Amendment Commissioner for Patents

P.O. Box 1450

Atty. Dkt.:

Alexandria, VA 22313-1450

Sir:

Reconsideration of the final rejections presented in the Examiner's Action mailed on May 25, 2005, is requested for the following reasons: